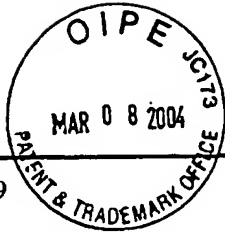


SHEET 1 OF 1

FORM PTO - 1449				ATTORNEY DOCKET NO.: DPL-043					
SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT				APPLICANT(S): Williams et al.					
				SERIAL NO.: 10/723,332					
				FILING DATE: November 26, 2003					
				CONFIRMATION NO: 9485					
				GROUP: 2859					
U.S. PATENT DOCUMENTS									
EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE		
<i>W</i>	A21	4,561,286	12/31/85	Sekler et al.	73	23	6/28/84		
<i>W</i>	A22	5,476,002	12/19/95	Bowers et al.	73	24.01	5/5/94		
<i>W</i>	A23	6,370,955 B1	4/16/02	Tuller et al.	73	579	11/29/99		
FOREIGN PATENT DOCUMENTS									
EXAM. INIT.		DOCUMENT NUMBER	DATE	COUNTRY CODE	CLASS	SUB CLASS	FILING DATE	ABSTRACT ONLY	ENGLISH LANG (Y/N)
<i>W</i>	B1	1034475	6/29/66	GB			3/26/64	N	Y
<i>W</i>	B2	01/77624 A2	10/18/01	PCT			4/5/01	N	Y
OTHER ART, JOURNAL ARTICLES, ETC.									
EXAM. INIT.	OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication)								
<i>W</i>	C6	Copy of International Search Report, PCT/US 03/38300, Mailing Date May 27, 2004.							
EXAMINER <i>C. Velazquez</i>					DATE CONSIDERED <i>10/18/04</i>				

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SHEET 2 OF 2

FORM PTO - 1449		ATTORNEY DOCKET NO. DPL-043	
INFORMATION DISCLOSURE STATEMENT		APPLICANT(S): Williams et al.	
		APPLICATION NO. 10/723,332	
		FILING DATE: November 25, 2003 GROUP: Not yet assigned	
OTHER ART, JOURNAL ARTICLES, ETC.			
EXAM. INIT.	OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication)		
<i>cu</i>	C1	RJ LEE microsystems™, NanoScale 9100™ User's Manual. <i>no date</i>	
	C2	SAW Sensor Seminar, Helsinki University of Technology (HUT), Material Physics Lab (May 2002).	
	C3	TA Instruments "Modulated Thermogravimetric Analysis: A new approach for obtaining kinetic parameters." <i>no date</i>	
	C4	TA Instruments brochure TGA 2050 Thermogravimetric Analyzer. <i>no date</i>	
<i>cu</i>	C5	TA Instruments, "Thermogravimetric Analysis" (TGA)," slide presentation. <i>no date</i>	

*G. Verchick**10/18/04*